



GaN Technology for Microwave Applications in Ka and Q bands

S. Delage

CAPABILITIES AND APPLICATIONS OF GaN DEVICES

Microwave and RF 2015



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- ▶ **LETI: A. Torres, D. Lafond**
- ▶ **UMS: D. Floriot, H. Blanck, J. Gruenenputt, B. Lambert, J.-P. Viaud...**
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- ▶ **LAAS: J.-G. Tartarin, S. D. Nsele LAAS**
- ▶ **Thales Alenia Space: J.-L. Muraro, S. Rochette, J.-L. Cazaux...**
- ▶ **Thales Com: J.Y. Daden, C. Voillequin**

▶ III-V Lab develops InAlN HEMT for wireless data transmission and high frequency power amplification: Ka, Q et E (30->86 GHz) Band.

- **Civil and military communication (SATCOM)**
- **Radars and altimeters**
- **Data backhauling**



▶ The applications are dual and are interesting both Alcatel-Lucent and Thales mother companies.

▶ Fierce competition is observed for these markets.

▶ Challenges :

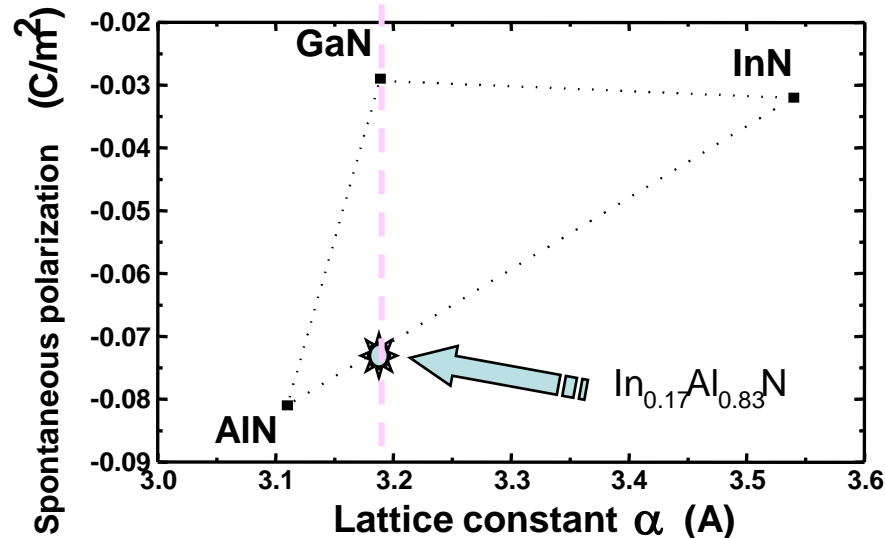
- **To increase power gain, efficiency and output power**
- **To achieve a sufficient level of maturity**
- **To transfer to manufacturing partners including UMS.**



Why did we believe in InAlN/GaN Heterostructure for Ultra High Power Microwave Applications ?

In_{0.18}Al_{0.82}N is lattice-matched to GaN

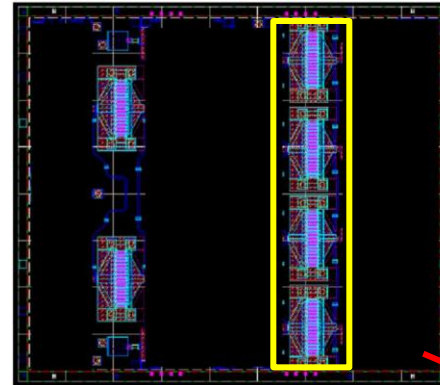
- Strong spontaneous polarisation allowing high density 2-D gas without mechanical stress,
- Improved reliability expected
- Flexibility for choosing barrier layer thickness (gate length – WBG thickness ratio), i.e. higher frequency achievable
- Possible higher 2D gas density (3A/mm for 0.25µm gate length)



► 3D-Thermal simulation at transistor and MMIC level

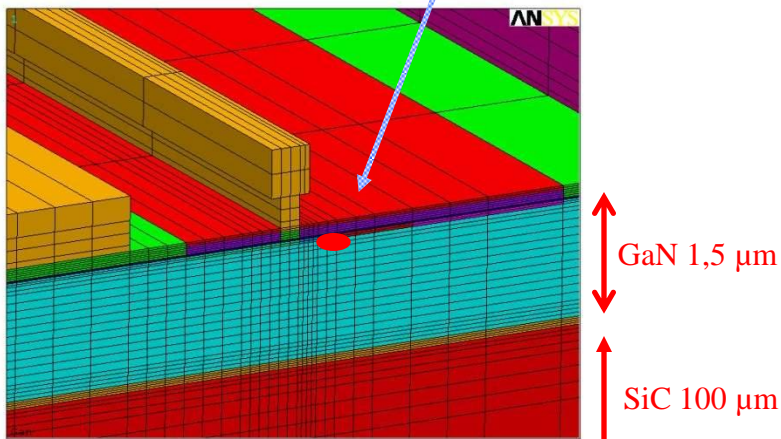
Material	Thermal conductivity (W/K.m) *
GaN	160
SiC	414
Si	155

* : at room temperature



Example of 100µm thick MMIC output power stage
1.92 mm CW – Ts=50°C

Dissipative Area



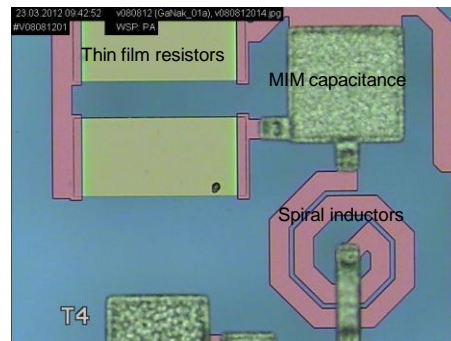
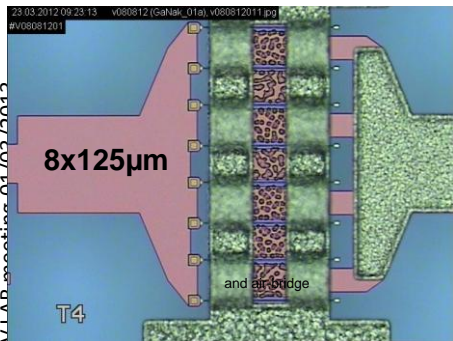
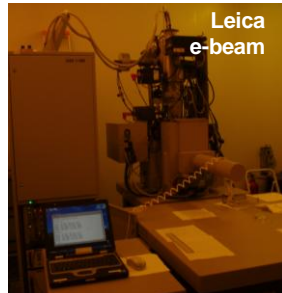
Performances at transistor level				
Ps	3W/mm	4W/mm	3W/mm	4W/mm
PAE	40%	40%	30%	30%
Pdiss	4 W/mm	5.4 W/mm	6.3 W/mm	8.4 W/mm
Rth Si/SiC	1.7			
Tj (GaN/SiC)	105	125	140	170
Tj (GaN/Si)	145	180	210	280

Ts=50°C sous la puce 100µm - etage de puissance HPA 1.92 mm (8x4x60)

► Rth GaN_Si/GaN_SiC ~ 1.7 -> Much lower maximum junction temperatures achieved with SiC substrates compared to Si ones

Technological steps	III-V Lab	UMS
Wafer cleaning and surface preparation	✓	
Alignment marks for UMS stepper		✓
Alignment marks for III-V lab : active device process (ohmics, isolation, gate, passivation, numbering)	✓	
Resistances, inter-connection, capacitor dielectric, pillars, bridge, back-side		✓
Measurements	✓	✓

SiC substrate lapping down to 100 μm by UMS
For both InAlN or AlGaN heterostructures

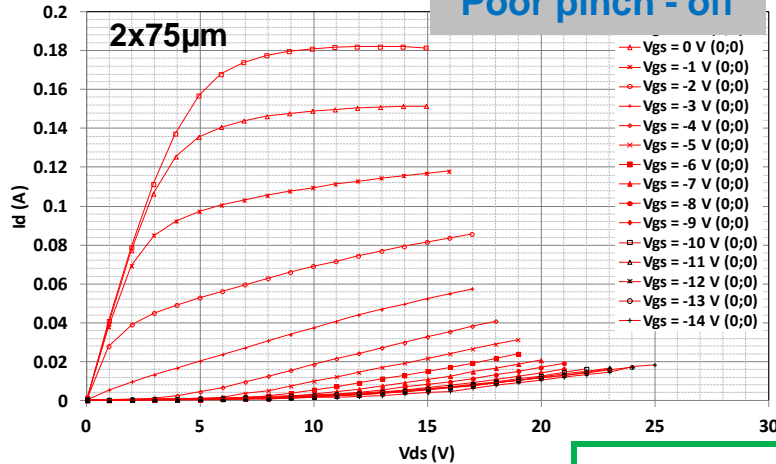


Realization of microstrip MMIC process and multifinger devices shared between III-V Lab and UMS

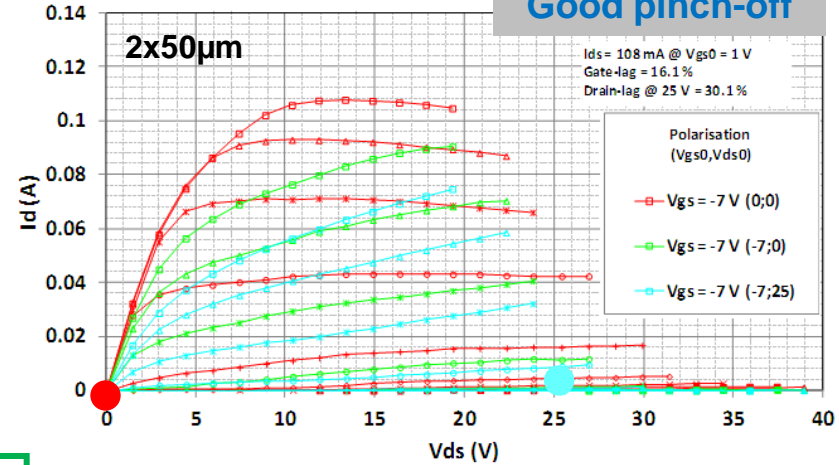
▶ **InAlN/GaN 0.15 μ m HEMT III-VLab Technology**

TS288W1_2x75

Poor pinch - off



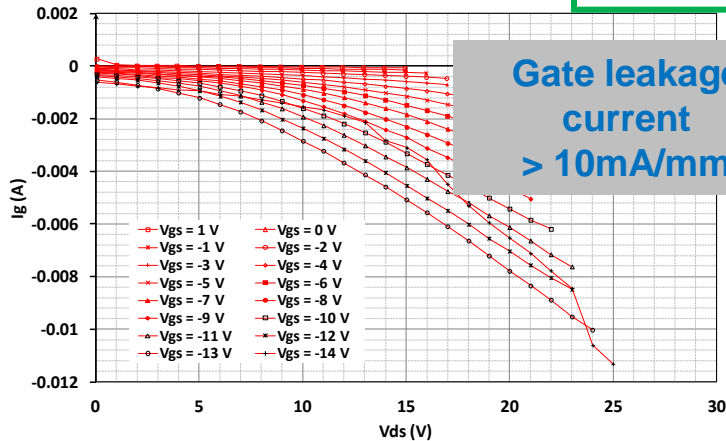
Good pinch-off



Improved buffer layer and passivation 2

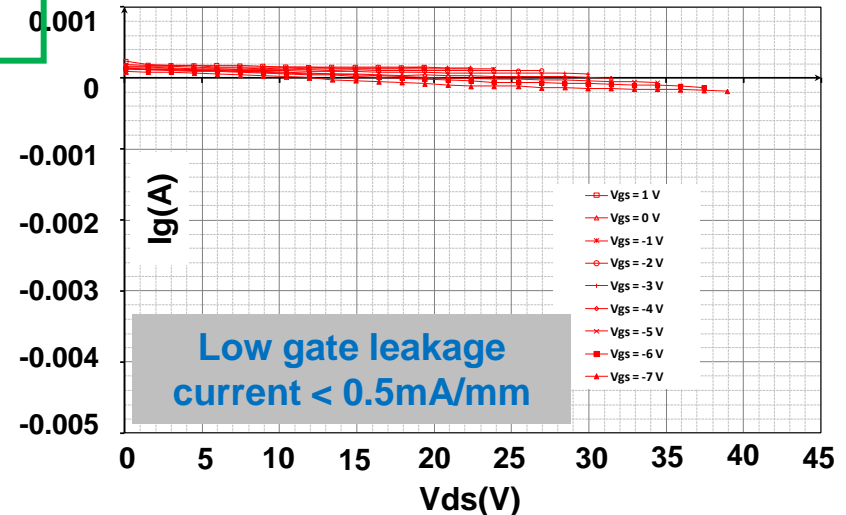
TS288W1 TS288W1_2x75_ARB

Gate leakage current > 10mA/mm



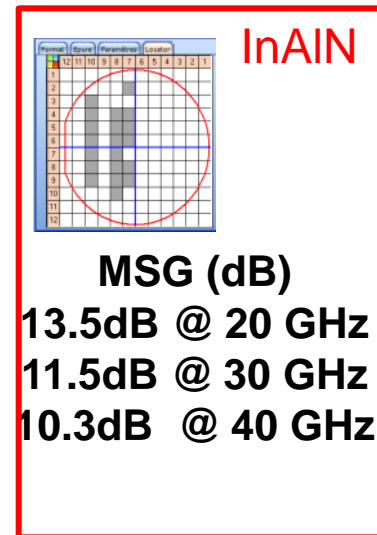
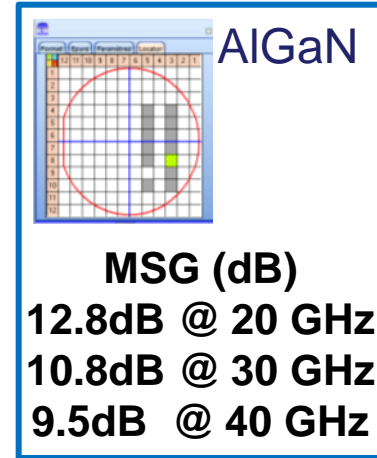
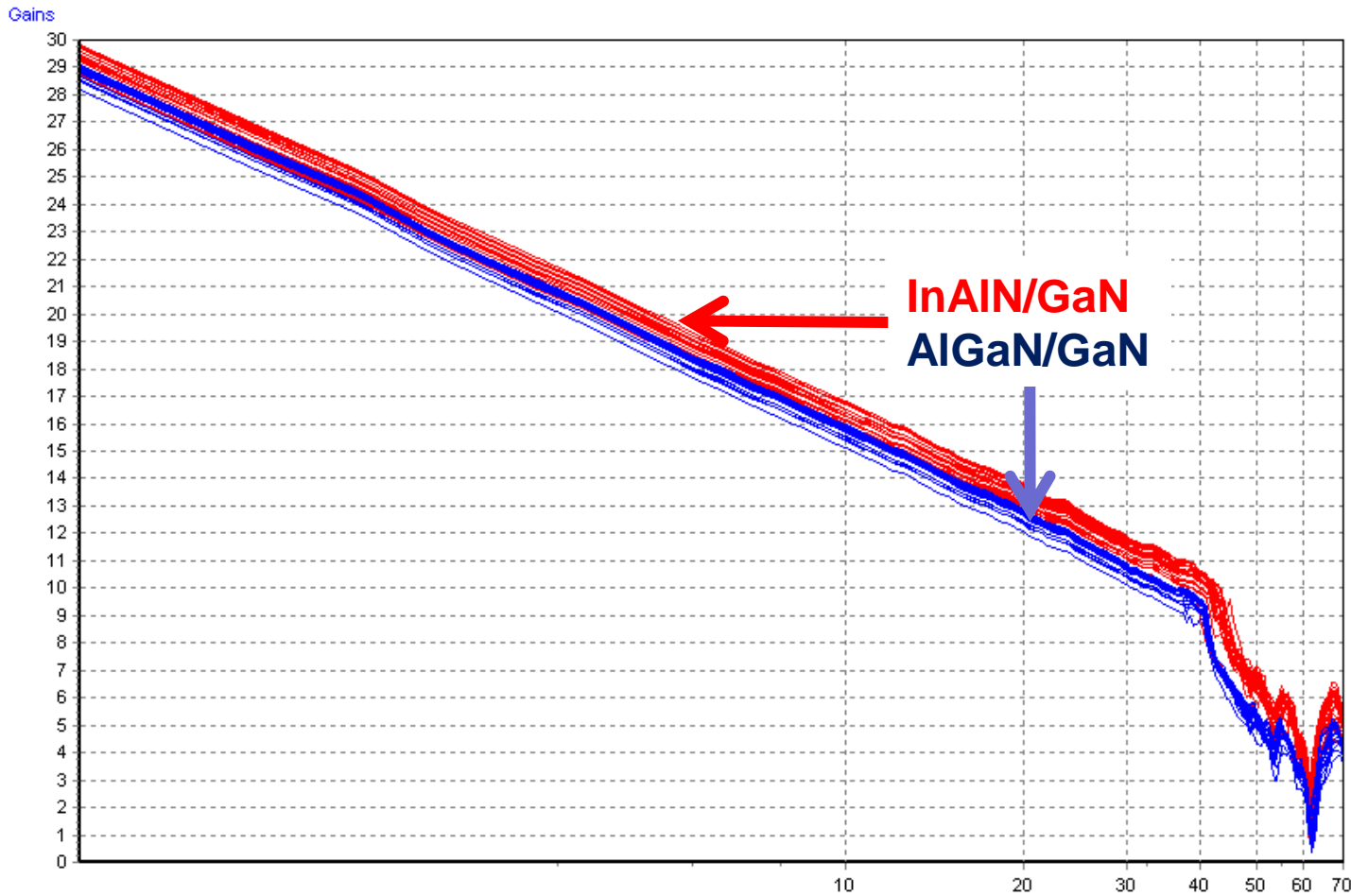
TS502 2x50_Lg0v15_ret109

Low gate leakage current < 0.5mA/mm



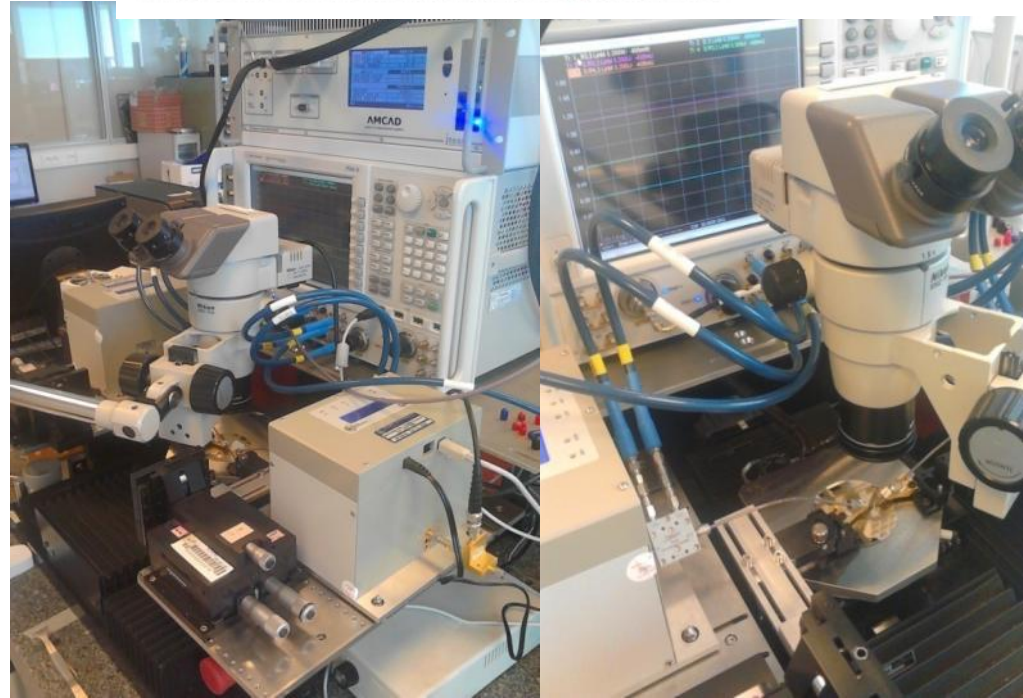
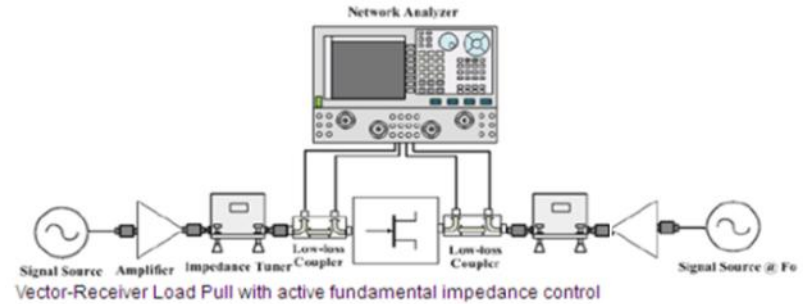
InAlN/GaN small signal power gains

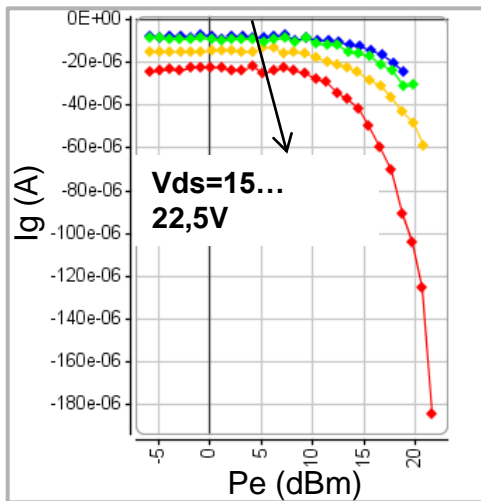
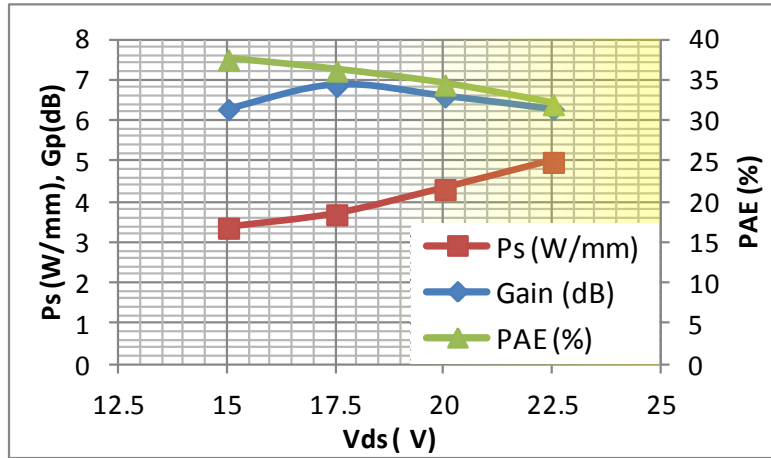
2x50 μ m x 0.15 μ m (CPW) 20V-200mA/mm



■ New equipment has been received in September 2014.

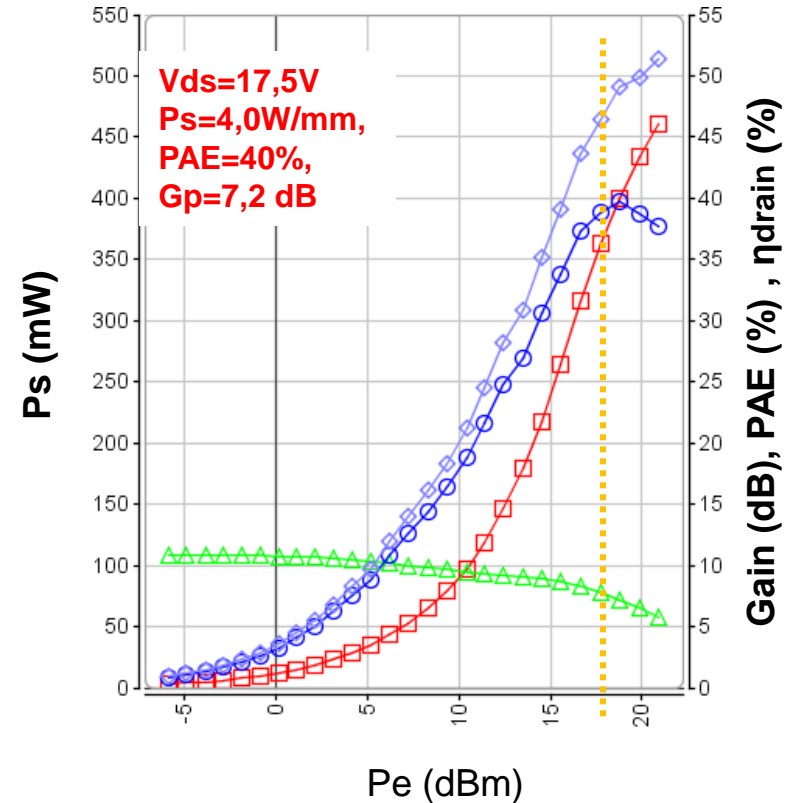
- Much faster than older bench limited to 18GHz,
- Capabilities to explore large topology variation thanks to active impedance matching,
- CW and pulses modes possible,
- Excellent reproducibility and precision.





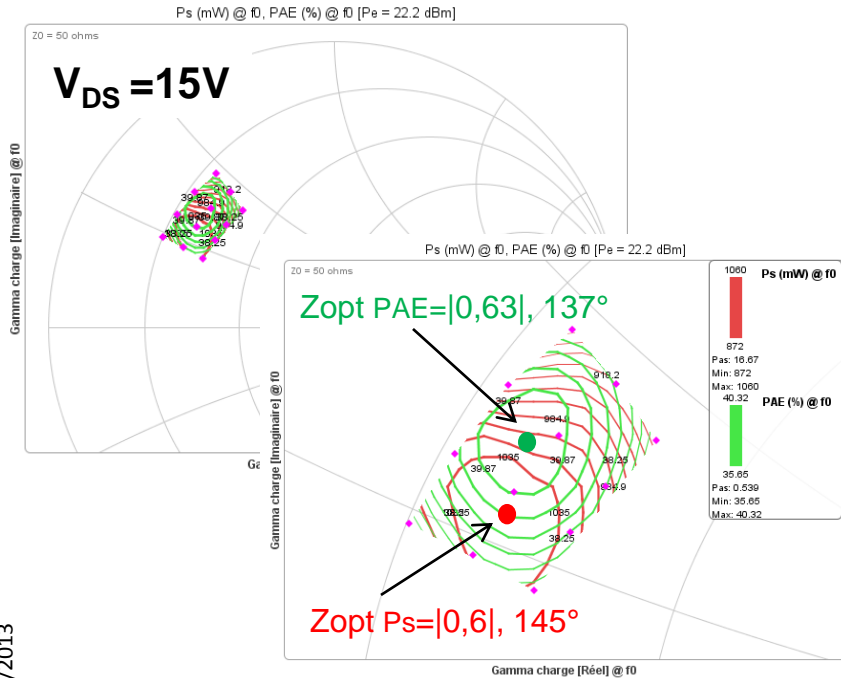
2x50x0.15μm, 30GHz dc/cw

AB)

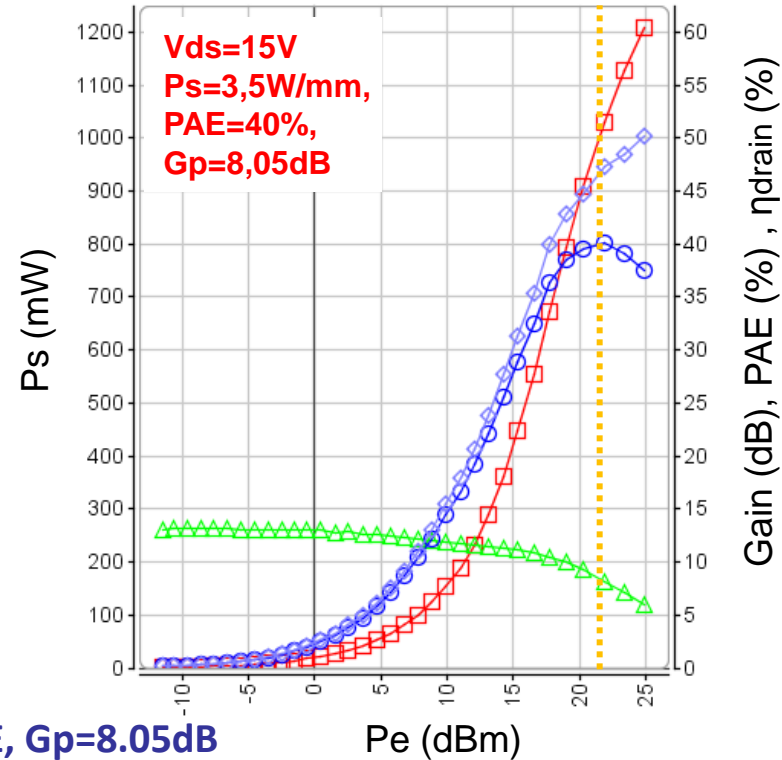


- Output power depends linearly with V_{ds}
- $V_{ds} < 20V$
- 4W/mm - 40% PAE - $V_{ds}=17.5V$
- Peak output power 5.12W/mm (34% PAE) at $V_{ds}=20V$

► **6x50 μ m Lg = 0.15 μ m (coplanar)**



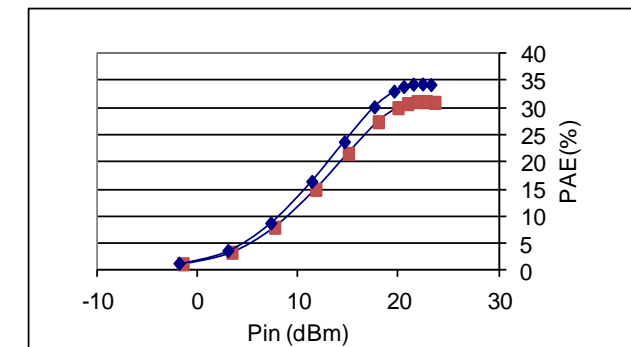
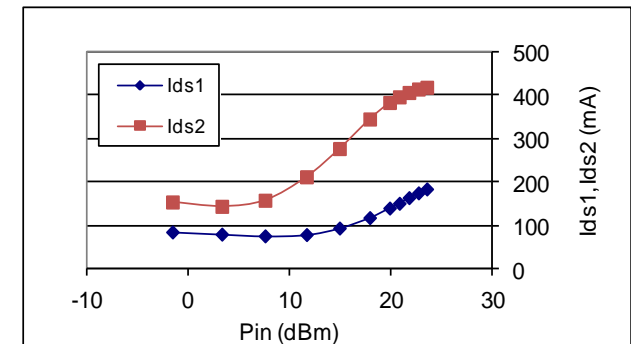
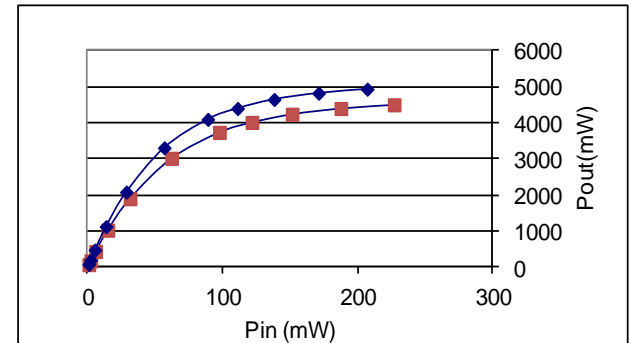
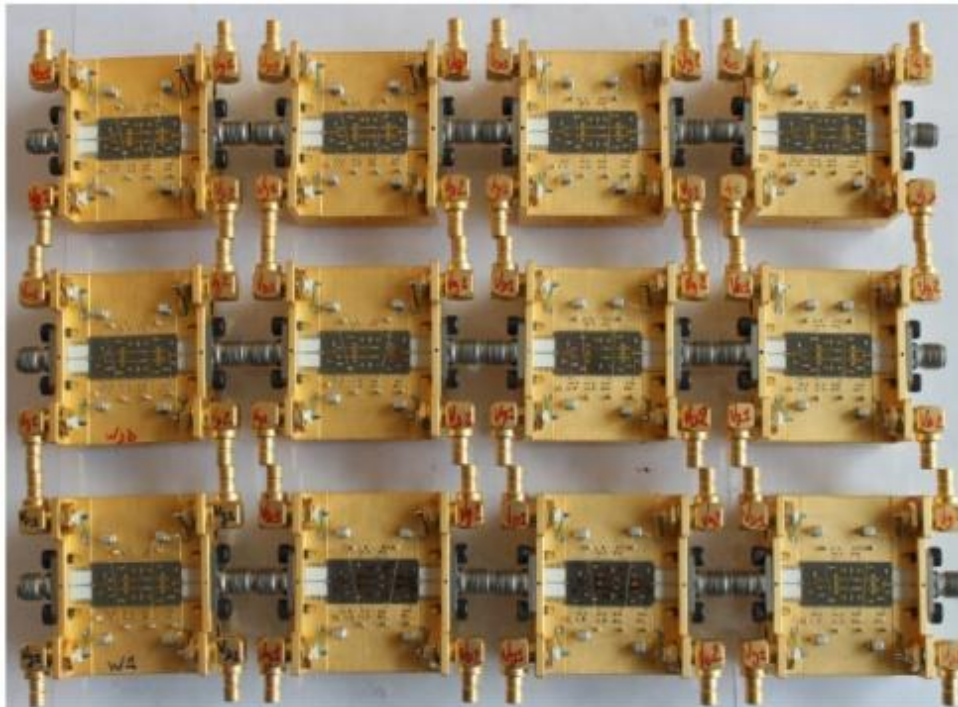
6x50x0,15 μ m 30GHz dc/cw



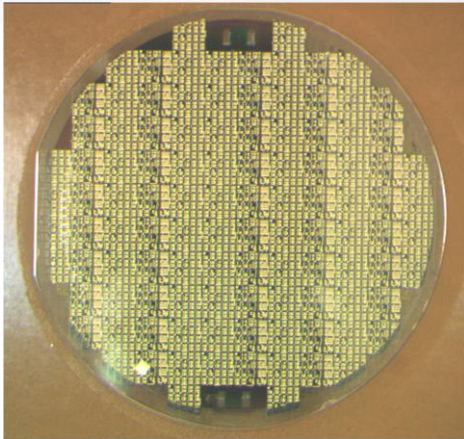
- Max Ps et PAE close, $|\Gamma_{opt}| \approx 0.6$
- Vds=15V: Ps=1045mW (3.5W/mm), PAE=40% PAE, Gp=8.05dB
- Vds=17.5V: 1270mW (4.25W/mm), PAE=36%, Gp=7.2dB

▶ **20GHz Hybrid Power Amplifier with flip-chipped HEMT mounting**

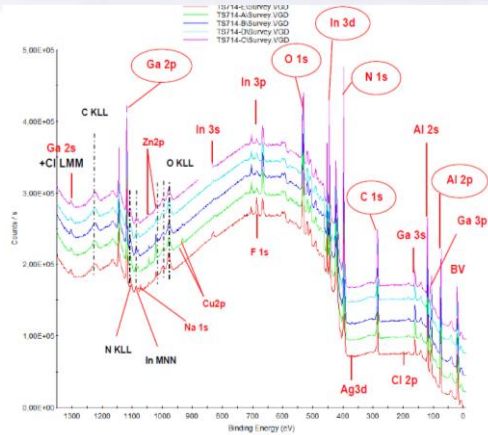
- ▶ $V_{ds1} = 18\text{ V}$, $V_{ds2} = 25\text{ V}$, classe AB
- ▶ @Max PAE :
- ▶ $P_{out} = 4.4\text{ W}$, PAE=31%, Gain=13.7dB



▶ Ka Band Low Noise and High Power Amplifiers



3" InAlN/GaN/SiC processed wafer
(III-V Lab / UMS)

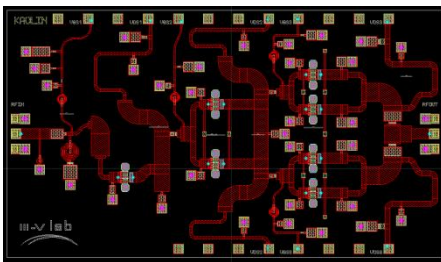
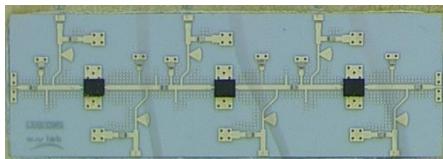


Chemical Analysis of GaN
devices (Institut Lavoisier)

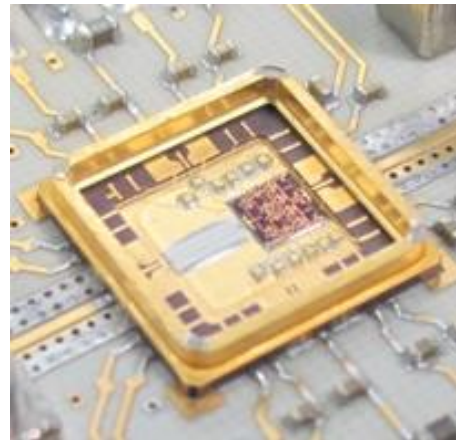
Start : 01.01.2011
End : 30.09.2014

III-V Lab contribution

- Project Management
- InAlN/GaN HEMT development
- Hybrid Ka-Band LNA (LAAS design)
- Ka Band HPA Design



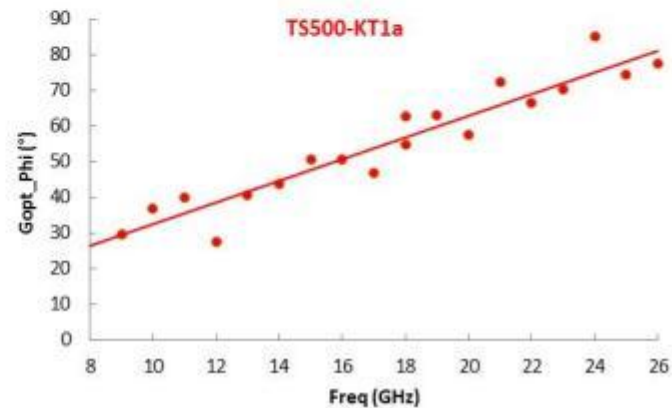
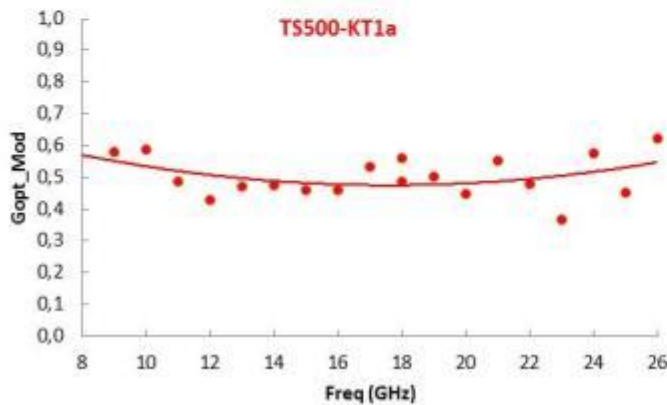
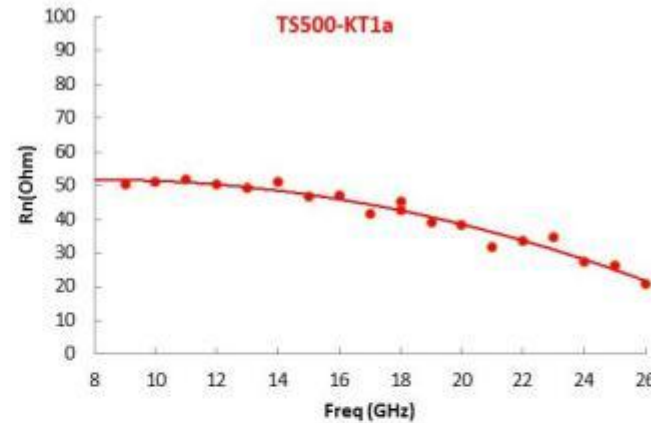
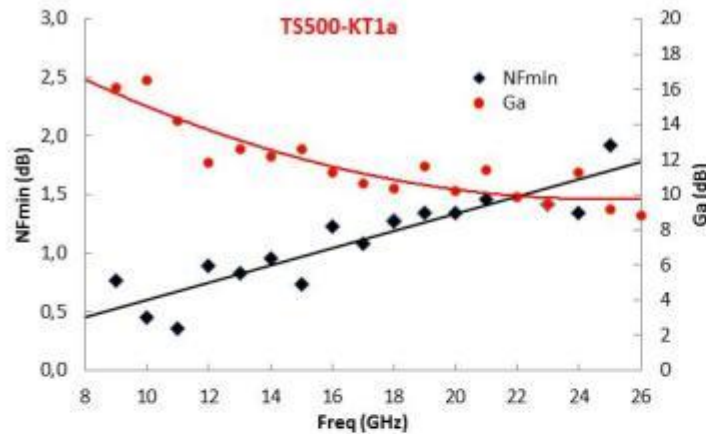
Ka Band amplifiers
(LAAS, III-V Lab)



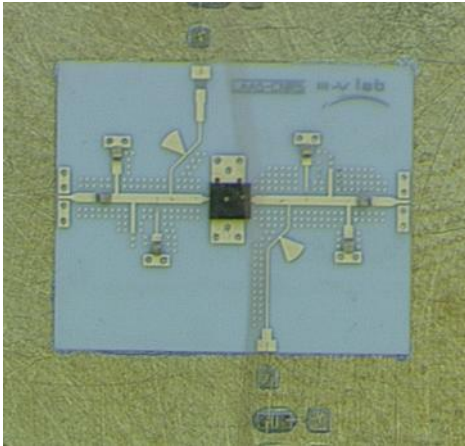
Ka Band package
(EGIDE, UMS, TCS)

Noise parameters of InAlN/GaN transistors (0,15 μm state of the art)

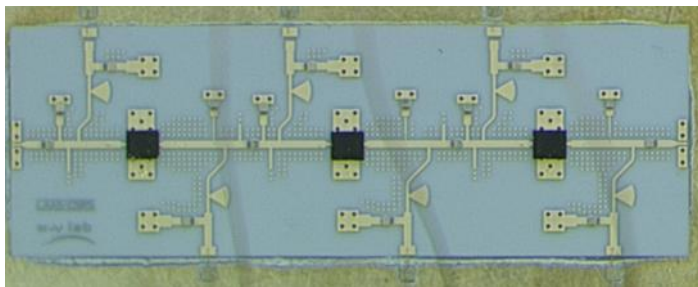
$NF_{min}=1.3$ dB et $Ga = 10.2$ dB @20 GHz



30 GHz LNA

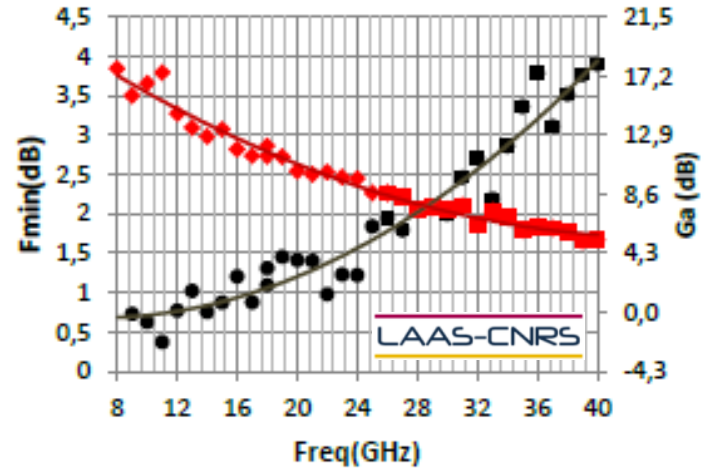


NF = 3.2dB @ 29.5 GHz
Gain = 5.6dB

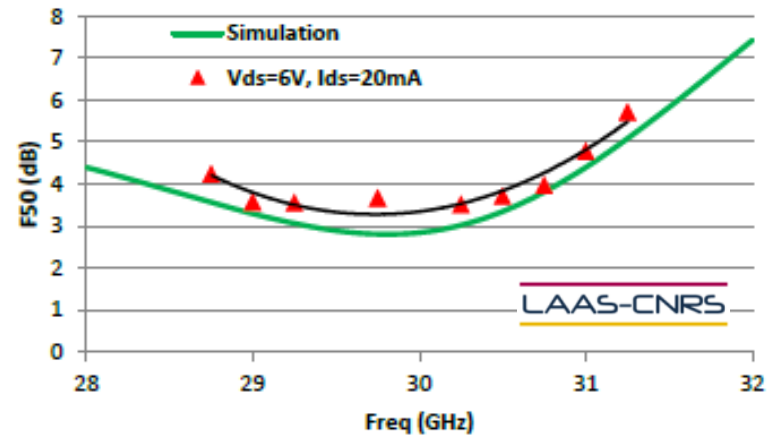


2x75μm

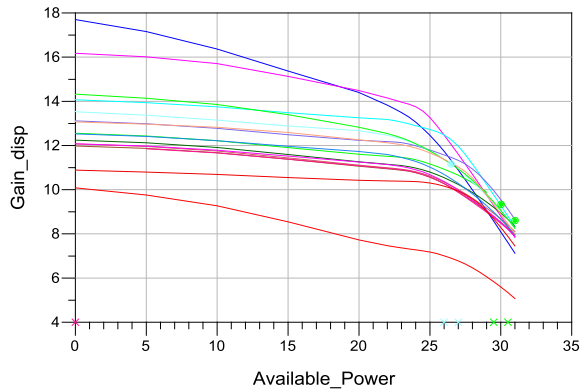
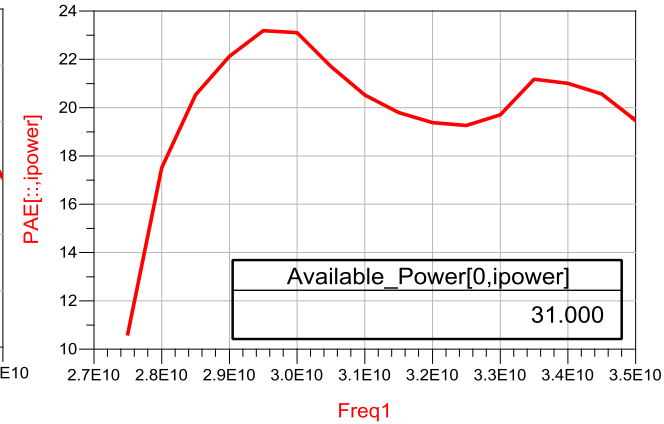
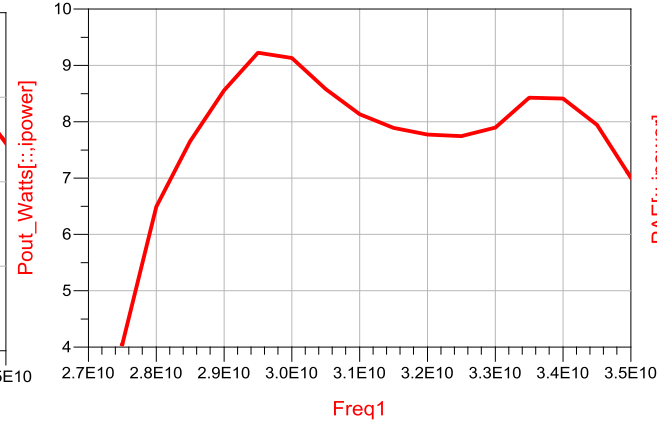
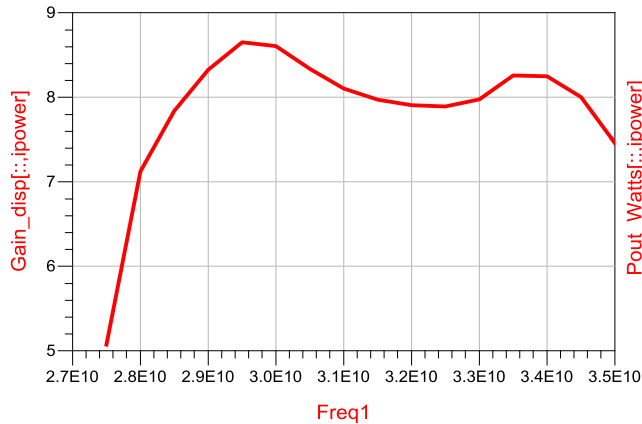
V_{ds}=6V



F50 (dB) LNA_1A



- ▶ **Compact NL model : 6x50 μ m : AlGaIn/GaN (March 2014)**
- ▶ **3.8W/mm – 33% PAE**
- ▶ **Different designs studied:**
 - 2 or 3 stages
 - Balanced architectures
 - [27.5-34.5 GHz] Bandwidth and divided in 2 subbands



- ▶ @Pin=31dBm, [28.5-34.5]GHz
- ▶ Pout>7.8W
- ▶ PAE~20-22%
- ▶ Gp>8dB (0.7dB ripple)

- ▶ **InAlN/GaN HEMT technology allows high frequency operation,**
- ▶ **Important work was carried out during the recent years to reach larger frequencies (heterostructure, gate length, passivation, topology, etc.) supported by experimental and simulations.**

- ▶ **Future**
 - Continue effort to mature 0.15 μm technology (coming EuGaNiC project),
 - Demonstrate MMIC for Ka and Q Bands (VEGaN-2 project),
 - Push further the gate length reduction ($\sim 0.08\mu\text{m}$) and optimisation of relevant device modules to address Q-Band and above frequencies.
 - Explore MMIC functionalities enrichment by adding Normally-off device cells.

Thank you for your attention !

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- EDA MANGA
- ANR VERSO Genghis Khan
- EU SPACE AlinWon
- CNES 20 GHz